

LISTING OF THE CLAIMS

The following Listing of the Claims replaces all previous listings of the claims within this application.

1. (currently amended) A computer assisted system for managing a work in process workload comprising:

means for storing identifying information for a microelectronic fabrication work in process workload lot;

means for accessing the identifying information for the work in process workload lot;

means for requesting and effecting a change in production of the work in process workload lot after accessing the identifying information for the work in process workload lot, wherein the means for requesting the change in production of the work in process workload lot provides for direct access by a customer.

2. (currently amended) ~~The system of claim 1 wherein the system is employed within a fabrication facility selected from the group consisting of electrical fabrication facilities, chemical fabrication facilities and mechanical fabrication facilities.~~ A computer assisted system for managing a work in process workload comprising:

means for storing identifying information for a chemical work in process workload lot;

means for accessing the identifying information for the work in process workload lot;

means for requesting and effecting a change in production of the work in process workload lot after accessing the identifying information for the work in process workload lot, wherein the means for requesting the change in production of the work in process workload lot provides for direct access by a customer.

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3. (original) The system of claim 1 wherein the system is employed within a microelectronic fabrication facility selected from the group consisting of integrated circuit microelectronic fabrication facilities, ceramic substrate microelectronic fabrication facilities, solar cell optoelectronic microelectronic fabrication facilities, sensor image array optoelectronic microelectronic fabrication facilities and display image array optoelectronic microelectronic fabrication facilities.

M 4. (original) The system of claim 1 wherein the change in production of the work in process workload lot is requested directly by the customer without an intervening approval by a customer engineer.

5. (original) The system of claim 1 wherein the computer assisted system is accessible by the customer through a distributed communications network.

6. (original) The system of claim 1 wherein the computer assisted system is accessible by the customer through an Internet distributed communications network.

7. (currently amended) A method for managing a work in process workload comprising:
providing a computer assisted system for managing a microelectronic fabrication work in process workload lot, the computer assisted system comprising:
means for storing identifying information for the work in process workload lot;
means for accessing the identifying information for the work in process workload lot; and

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means for requesting and effecting a change in production of the work in process workload lot after accessing the identifying information for the work in process workload lot, wherein the means for requesting the change in production of the work in process workload lot provides for direct access by a customer; and

requesting the change in production of the work in process workload lot directly by the customer.

8. (currently amended) ~~The method of claim 7 wherein the system is employed within a fabrication facility selected from the group consisting of electrical fabrication facilities, chemical fabrication facilities and mechanical fabrication facilities.~~ A method for managing a work in process workload comprising:

providing a computer assisted system for managing a chemical work in process workload lot, the computer assisted system comprising:

means for storing identifying information for the work in process workload lot;

means for accessing the identifying information for the work in process workload lot; and

means for requesting and effecting a change in production of the work in process workload lot after accessing the identifying information for the work in process workload lot, wherein the means for requesting the change in production of the work in process workload lot provides for direct access by a customer; and

requesting the change in production of the work in process workload lot directly by the customer.

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9. (original) The method of claim 7 wherein the system is employed within a microelectronic fabrication facility selected from the group consisting of integrated circuit microelectronic fabrication facilities, ceramic substrate microelectronic fabrication facilities, solar cell optoelectronic microelectronic fabrication facilities, sensor image array optoelectronic microelectronic fabrication facilities and display image array optoelectronic microelectronic fabrication facilities.

A 10. (original) The method of claim 7 wherein the change in production of the work in process workload lot is requested directly by the customer without an intervening approval by a customer engineer.

11. (original) The method of claim 7 wherein the computer assisted system is accessible by the customer through a distributed communications network.

12. (original) The method of claim 7 wherein the computer assisted system is accessible by the customer through an Internet distributed communications network.
